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on November 4, 2009

TOWNSEND and TOWNSEND and CREW LLP

By: /Sherry Soares/  
Sherry Soares

PATENT  
Docket No.: A7600P1/T51700  
Client Ref. No.: 7600/P1/DSM/HDP/CVD/JPFEIFER  
TTC No.: 016301-051700US

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Hemant P. Mungekar, et al.

Patent No.:

Issued:

Application No.: 10/660,813

Filed: September 12, 2003

For: REACTIVE ION ETCHING FOR  
SEMICONDUCTOR DEVICE  
FEATURE TOPOGRAPHY  
MODIFICATION

Customer No.: 57385

Confirmation No.: 7055

Examiner: Rodney Glenn McDonald

Art Unit: 1795

**RESPONSE TO NOTICE TO FILE  
CORRECTED APPLICATION PAPERS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Commissioner:

Pursuant to the Notice to File Corrected Application Papers mailed on  
November 29, 2009, enclosed are the following to be made of record in the above-identified  
application:

- 1) Replacement Drawing Sheet
- 2) Annotated Drawing Sheet Showing Changes
- 3) Copy of Notice to File Corrected Application Papers

No fees are believed due with this response, however, the Commissioner is hereby authorized to charge any additional fees or credit any overpayment in connection with this paper to Deposit Account No. 20-1430.

Respectfully submitted,

/Jason A. Sanders/

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